## 2단계 모세관 리소그라피 기술을 이용한 마이크로/나노스케일 복합 구조의 제조 및 표면 특성 분석

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## Fabrication of multiscale hierarchical structures by two-step temperature-directed capillary lithography

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Key Words: micro/nano hierarchical structure (마이크로/나노 병합구조), capillary lithography (모 세관 리소그라피), hydrophobicity (소수성), contact angle (접촉각)

Abstract: In this paper, a simple method for fabricating micro/nanoscale combined hierarchical structures is presented using a two-step temperature-directed capillary molding technique. This lithographic method consists of two steps: (i) fabrication of polymer microstructures using a PDMS mold and (ii) subsequent nanofabrication using a high-resolution polyurethane acrylate (PUA) mold on top of the pre-formed microstructures. The resulting micro/nano combined structures were robust and demonstrated enhanced water-repellent properties by coexistence of homogeneous and heterogeneous wettings, as confirmed by contact angle measurement of water. An analytical model was suggested to explain our experimental observations and shows a good agreement with the experimental results.

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## Simulation of polymer deformation in nanoimprint lithography

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Key Words: nanoimptint lithography(나노임프린트 리소그래피), surface tension(표면 장력), dynamic contact angle(동적 접촉각), slip length, PMMA

Abstract: Numerical simulations are carried out to understand the deformation process of thin polymer (PMMA) film in nanoimprint lithography. Deformation of a thin polymer above its glass transition temperature is studied for various imprinting conditions such as the aspect ratios of a mold pattern, and imprinting velocity. And, the difference of the thermal expansion coefficients between the mold and the substrate causes strain, and relationship between the strain concentration and defects in the pattern is studied.